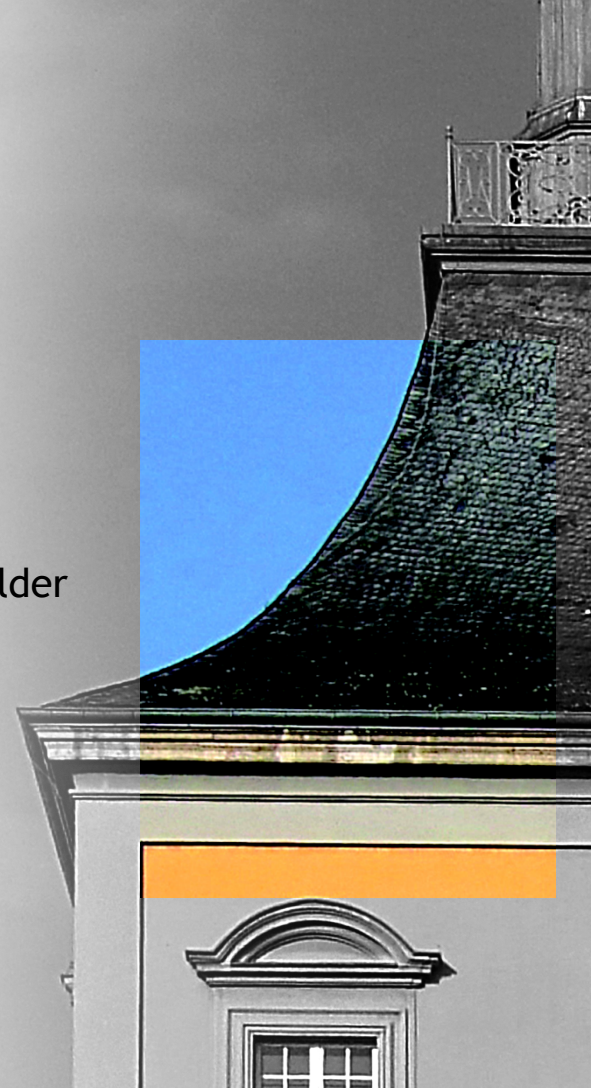


MEASUREMENTS OF INTER-PIXEL RESISTANCE

Sinuo Zhang*, Sabine Hartung, David-Leon Pohl, Jochen Dingfelder

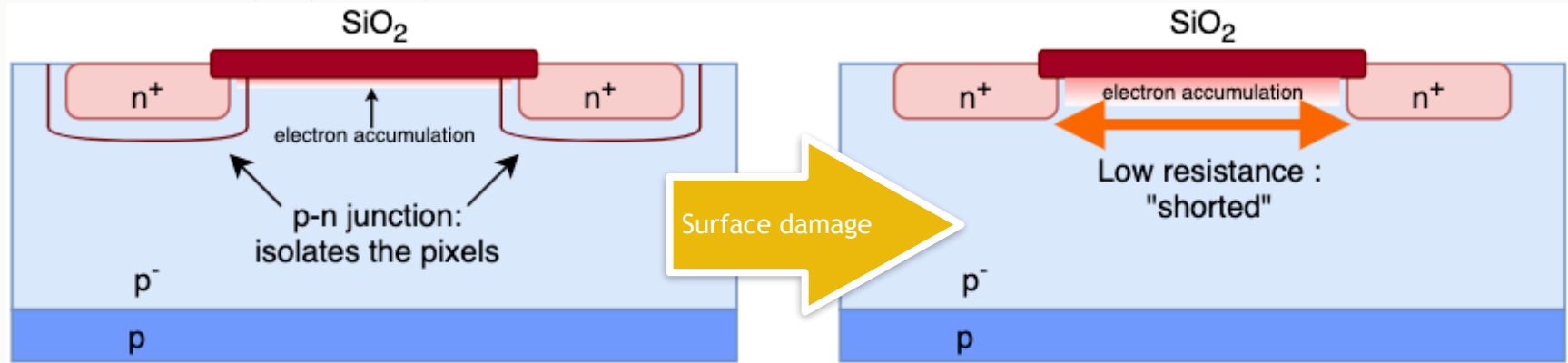
20.11.2020, 37th RD50 Workshop

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ISOLATION BETWEEN ELECTRODE IMPLANTS

- **shorted electrodes degrade the spatial resolution**
- N-on-P sensors: p-type bulk provides a natural isolation



- Electron accumulation layer can present beneath the oxide (figures are not in scale)
→ **higher bias voltages** can mitigate this problem*
- **Surface damage after irradiation*** → higher concentration of oxide charge & interface traps
→ more pronounced electron accumulation → reduction of the inter-pixel resistance

*A.Dirlamm et al(2020): <https://indico.cern.ch/event/813597/contributions/3727777/>
(more previous studies can be found in the references of this presentation)

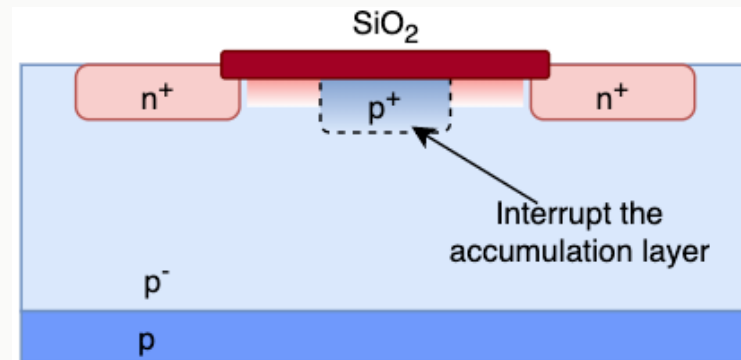
P-STOP ISOLATION

- **P-stop** or p-spray isolation in passive sensors is (more or less) a default implementation, since it can:

- shape the E-field between pixels
- enhance the inter-pixel isolation

- **Problem: p-stop can introduce higher pixel capacitances**

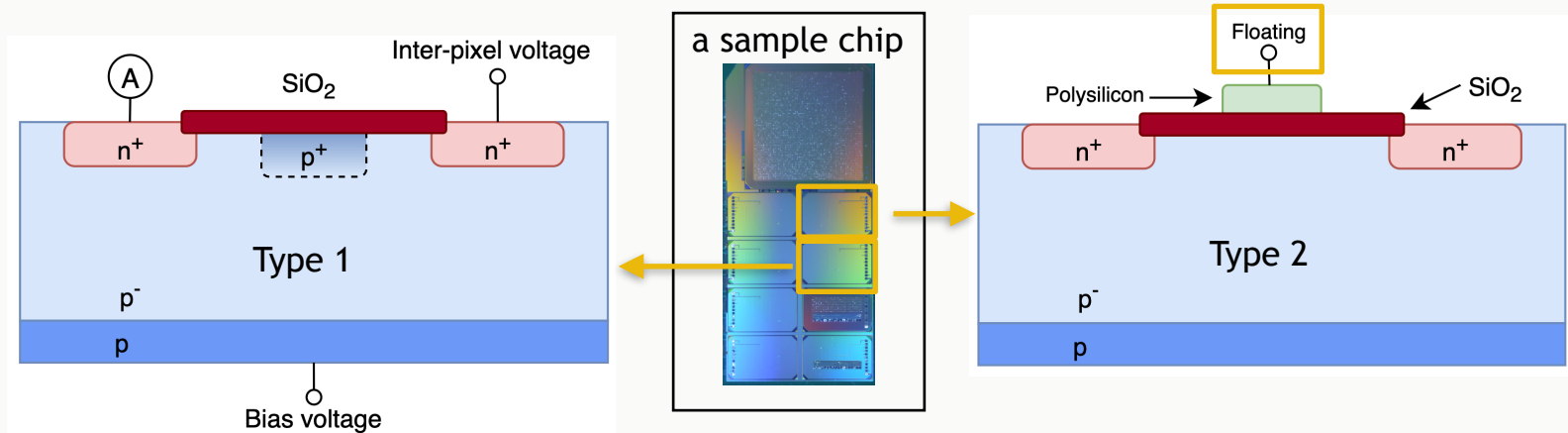
H. Krüger and E. Kimmerle (2020): <https://arxiv.org/abs/2010.03267>



- ➔ How large is the impact of the p-type isolation?
- ➔ After proton irradiation?
- ➔ If p-stops can be removed → lower pixel capacitance: a great advantage for timing resolution, power consumption, and electronic noise

TWO TYPES OF STRUCTURES

- From **passive CMOS sensor** test-structures fabricated in LFoundry 150 nm CMOS technology
- CZ wafer, thickness = $200\ \mu\text{m}$, pixel size = $50 \times 250\ \mu\text{m}^2$
- **Major difference** is the structure of the inter-pixel region:
 - type 1: p-stop
 - type 2: no p-stop; poly silicon layer above the oxide (**field-plate**).
voltage can be applied at poly silicon to modify the field beneath (**floating** this time)



PREPARATION OF SAMPLES

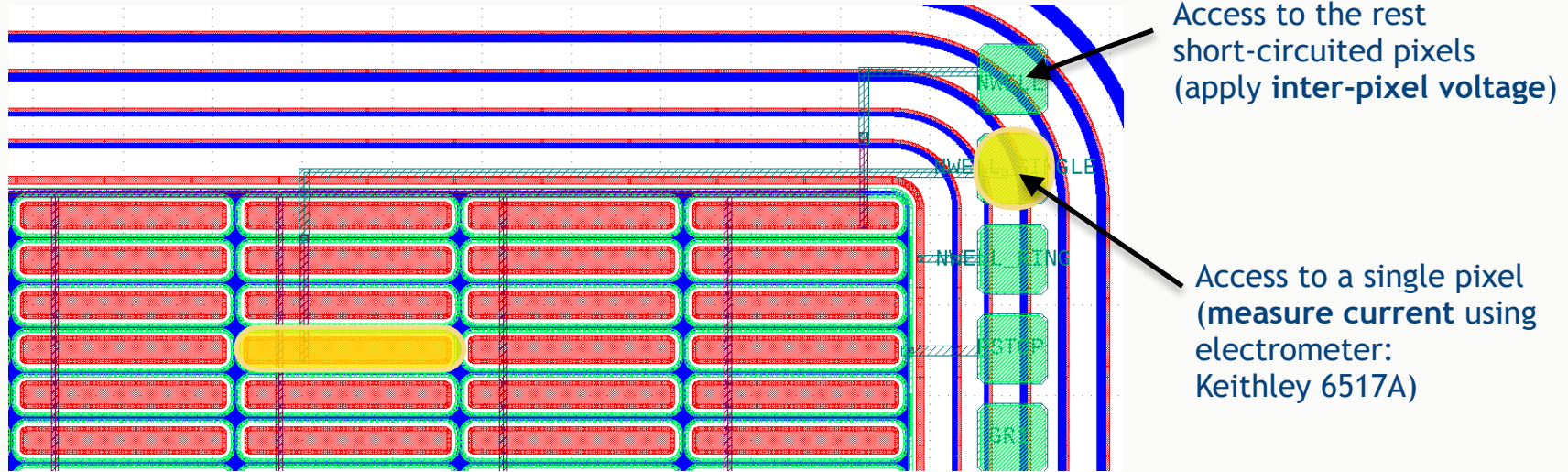
- 15 samples for measurements:
 - 3 unirradiated samples
 - 3 samples for each fluence:
 - $5 \times 10^{14} \text{ neq cm}^{-2}$ (one chip is damaged)
 - $1 \times 10^{15} \text{ neq cm}^{-2}$
 - $5 \times 10^{15} \text{ neq cm}^{-2}$
 - $1 \times 10^{16} \text{ neq cm}^{-2}$
- Facility for irradiation:
 - 14 MeV protons from cyclotron at Bonn



The Bonn Isochronous Cyclotron at Helmholtz Institut für Strahlen- und Kernphysik

P. Wolf et al. (2019): <https://indico.cern.ch/event/855994/contributions/3637076/>

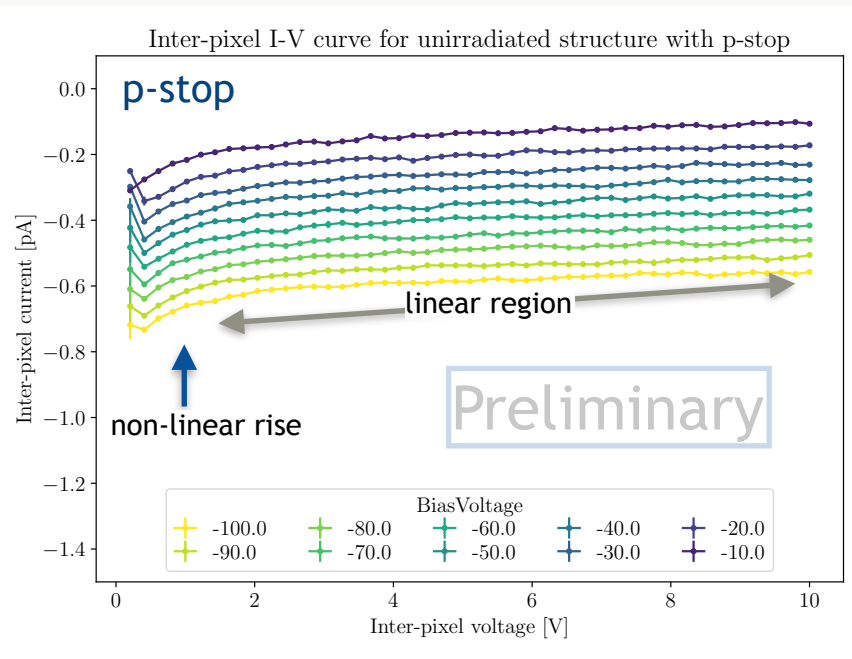
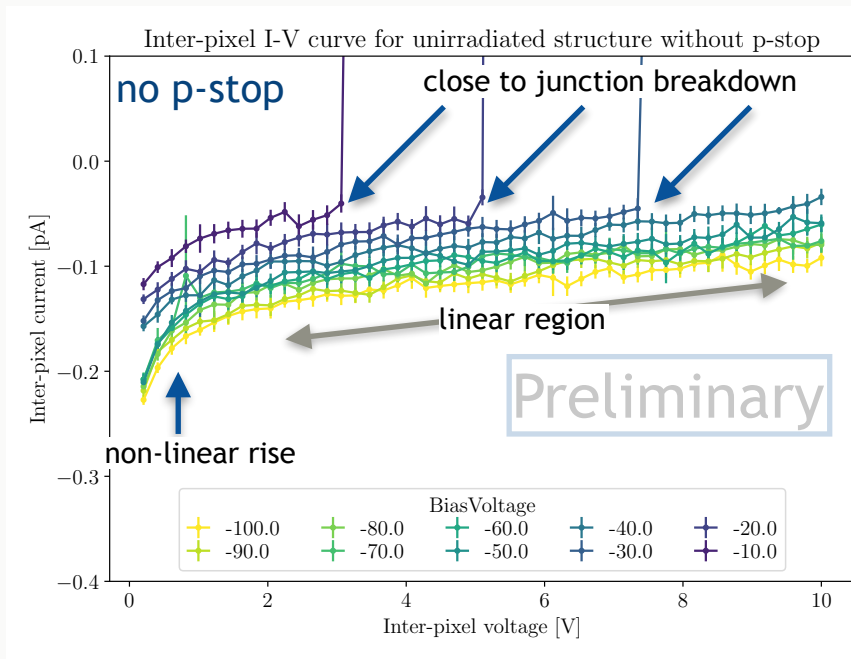
MEASURING TEST-STRUCTURES



- Electrode implant (N-well) of the highlighted pixel can be accessed independently
- The N-wells of the rest pixels are short-circuited through a metal grid
- Measure the current-voltage behaviour **between one pixel and the surrounding pixels**
- Evaluate the resistance through fitting the inter-pixel I-V curve

INTER-PIXEL I-V BEFORE IRRADIATION

- Shows characteristics of p-n junctions
- Fitting of the linear region delivers the inter-pixel resistance

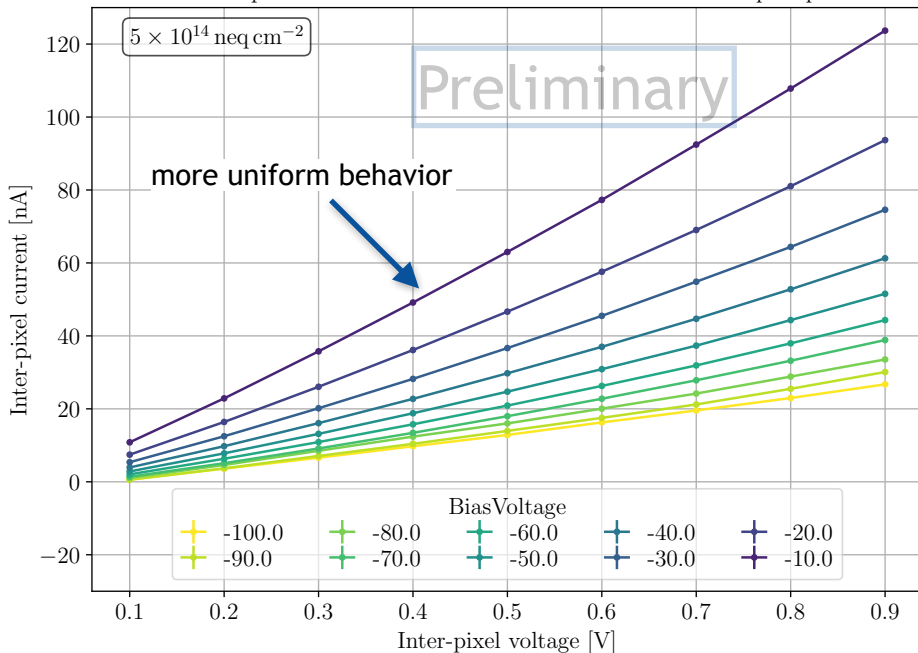


INTER-PIXEL I-V AFTER IRRADIATION

- Shows more uniform (linear) behavior, especially for higher bias voltages

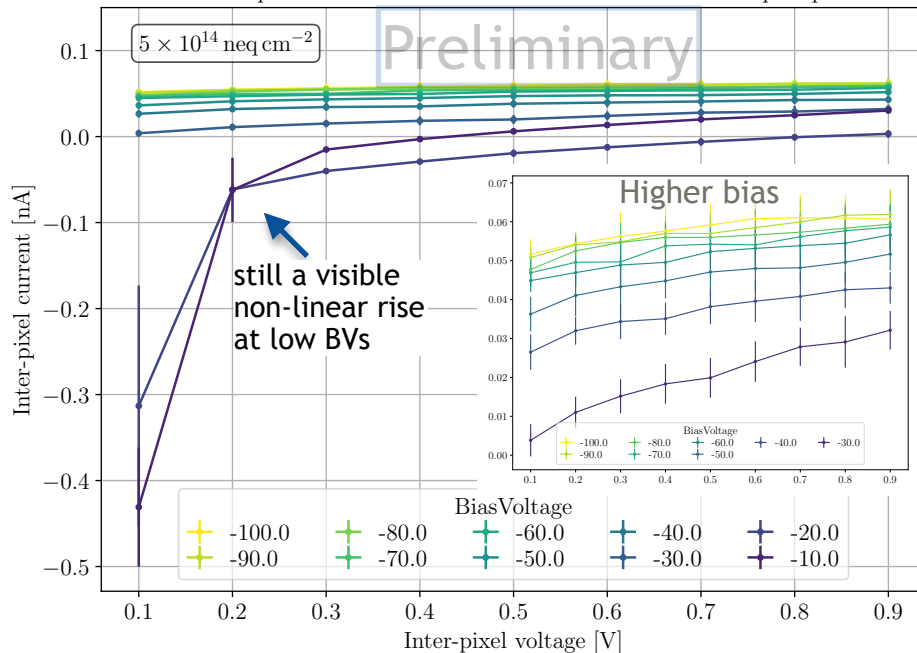
no p-stop

Inter-pixel I-V curve for unirradiated structure without p-stop



p-stop

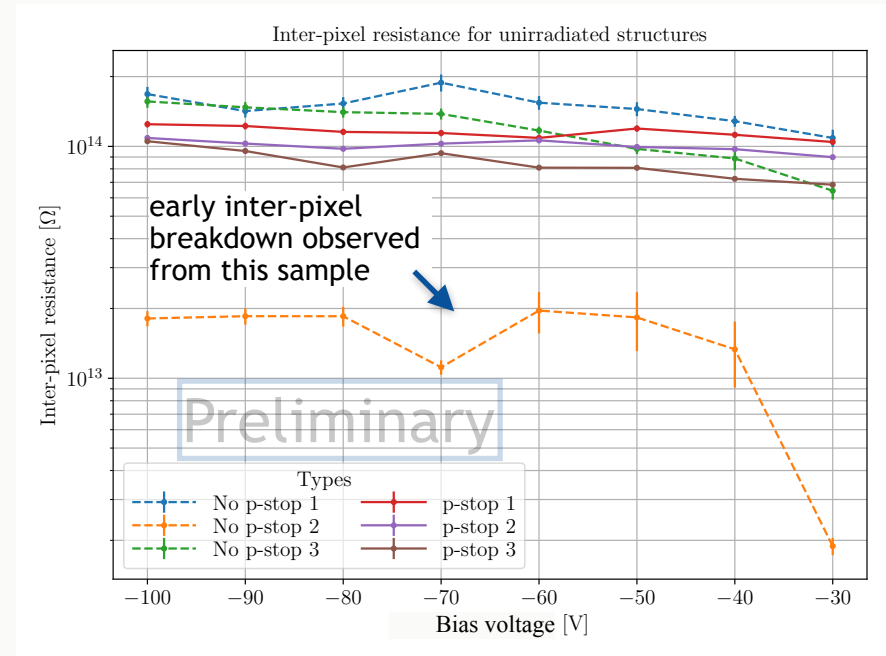
Inter-pixel I-V curve for unirradiated structure without p-stop



INTER-PIXEL RESISTANCE BEFORE IRRADIATION

- Measured at $T \approx 20^\circ \text{C}$ (293 K)
- **WITH** p-stop (solid lines):
 - resistances are approximately $1 \times 10^{14} \Omega$
- **WITHOUT** p-stop (dashed lines):
 - 2 samples reveal a similar resistance of $1 \times 10^{14} \Omega$
 - One sample has a lower resistance, the difference is approximately 1 order of magnitude
 - this sample shows an early breakdown at approximately 3 V inter-pixel voltage

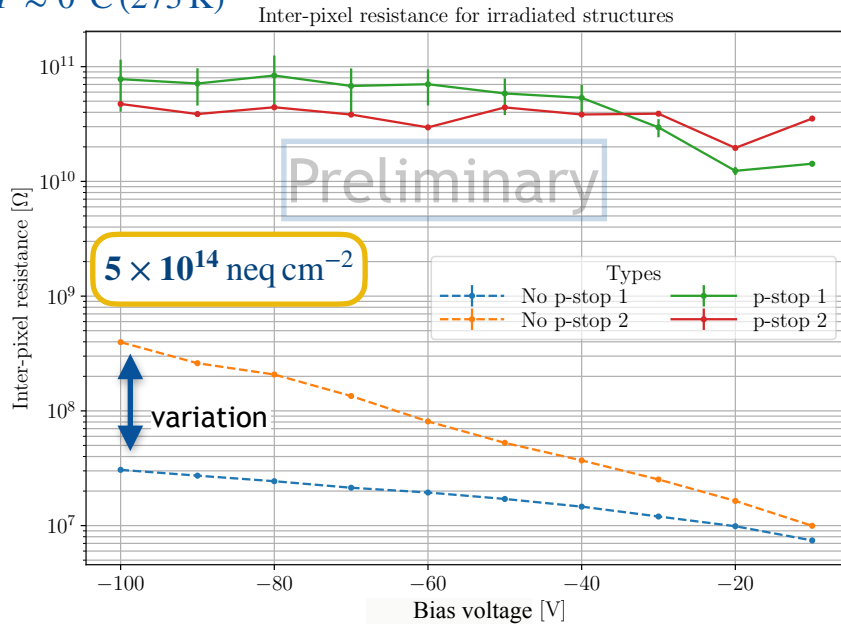
➔ Before irradiation, high inter-pixel resistance can be achieved without using p-stop



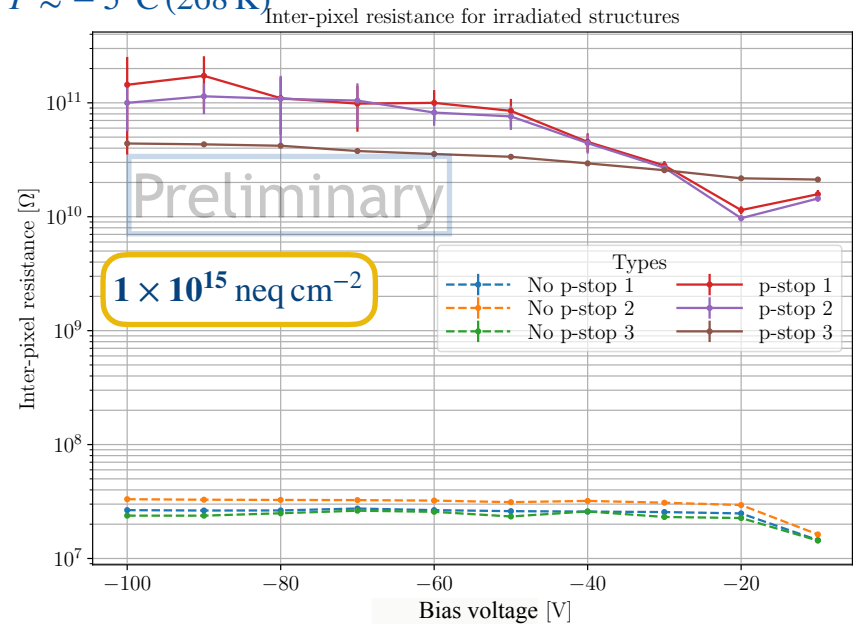
INTER-PIXEL RESISTANCE AFTER IRRADIATION (LOWER FLUENCES)

- Decrease of resistance is observed (WITH p-stop: solid lines; WITHOUT p-stop: dashed lines)
- Increases with bias voltage
- P-stop provides a higher resistance

$T \approx 0^\circ \text{C}$ (273 K)



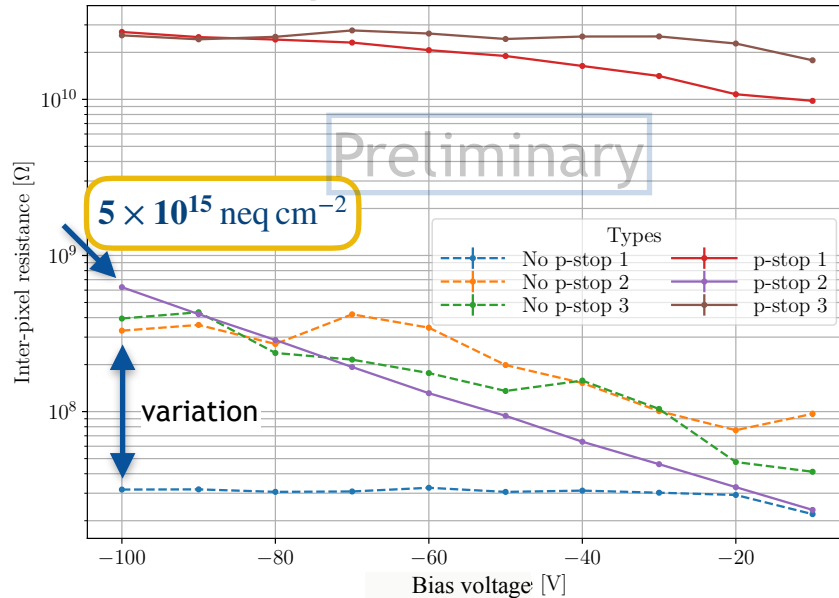
$T \approx -5^\circ \text{C}$ (268 K)



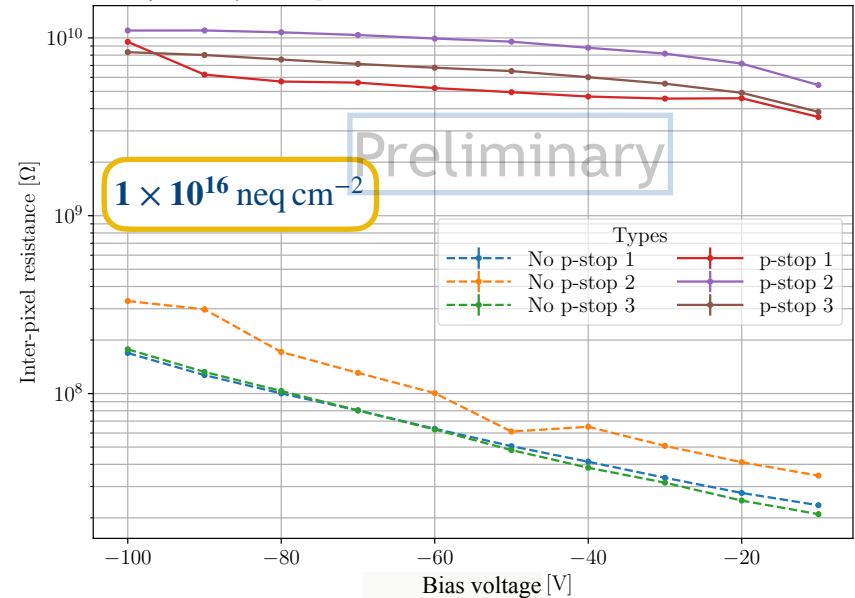
INTER-PIXEL RESISTANCE AFTER IRRADIATION (HIGHER FLUENCES)

- Resistances are similar as with lower fluences (**WITH p-stop: solid lines; WITHOUT p-stop: dashed lines**)
- Increases with bias voltage; p-stop provides a higher resistance
- A sample **WITH** p-stop gives unusually low resistance (left figure, label: “p-stop 2”), guess: malfunctioning sensor

$T \approx -12^\circ \text{C}$ (261 K) Inter-pixel resistance for irradiated structures



$T \approx -11^\circ \text{C}$ (262 K) Inter-pixel resistance for irradiated structures



SUMMARY OF THE PRELIMINARY RESULTS

Fluence	Resistance BV=-100 V	Resistance (p-stop) BV=-100 V	Temperature & Relative Humidity
0	$\sim 10^{13} - 10^{14} \Omega$	$\sim 10^{14} \Omega$	$\approx 293 \text{ K} \ \& \ \approx 8 \% \text{ RH}$
$5 \times 10^{14} \text{ neq cm}^{-2}$	$\sim 10^7 - 10^8 \Omega$	$\sim 10^{10} \Omega$	$\approx 273 \text{ K} \ \& \ \approx 12 \% \text{ RH}$
$1 \times 10^{15} \text{ neq cm}^{-2}$	$\sim 10^7 \Omega$	$\sim 10^{11} \Omega$	$\approx 268 \text{ K} \ \& \ \approx 13 \% \text{ RH}$
$5 \times 10^{15} \text{ neq cm}^{-2}$	$\sim 10^7 - 10^8 \Omega$	$\sim 10^8 - 10^{10} \Omega$	$\approx 261 \text{ K} \ \& \ \approx 13 \% \text{ RH}$
$1 \times 10^{16} \text{ neq cm}^{-2}$	$\sim 10^8 \Omega$	$\sim 10^{10} \Omega$	$\approx 262 \text{ K} \ \& \ \approx 15 \% \text{ RH}$

- High resistance before irradiation at 293 K

- No significant changes between different fluences at similar temperatures

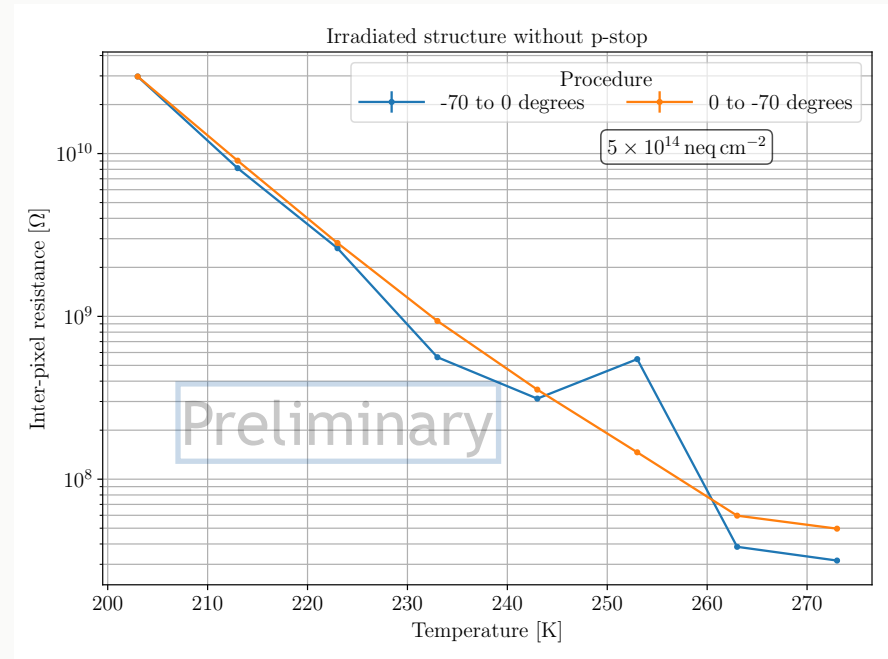
- Resistance decreases by approximately 6 orders of magnitude
- Large variation among samples is observed

- Resistance decreases by approximately 3 orders of magnitude
- Stable among samples

PROBLEMS & QUESTIONS

- Large variation of resistance among samples:
 - appears often for the sensors **WITHOUT** p-stop
 - assumption:
the floating poly silicon field-plate may “pick up” different unknown voltages for each measurement
- Temperature dependent resistance
 - a test of an irradiated sample at $T \in [203, 273]$ K
 - resistance increases (exponentially) with decreasing temperature
 - ➔ systematic error of the measurement
 - ➔ What is the main mechanism of this effect?
Mobility?
Generation & recombination?
Issue of the measurement setup?

Test: irradiated sensor without p-stop at $BV = -100$



FUTURE INVESTIGATIONS

- Temperature dependent resistance:
 - perform measurements at the same temperature
 - take into account the systematic error
 - search for the main mechanism
- Apply voltages at the field-plate:
 - determine the influence on the resistance
 - search for optimum potentials
- Contribution from TID
 - X-ray irradiation (Bonn) up to ~1 Mrad (Saturation of oxide charge)

SUMMARY & CONCLUSION

- Inter-pixel resistance of passive CMOS test structures with two different types of inter-pixel isolation have been measured before and after proton irradiation
- Resistance BEFORE irradiation:
 - test-structures WITH & WITHOUT p-stop reveal a similar value in the order of $10^{14} \Omega$
 - ➔ ability of isolation is the same
- Resistance AFTER irradiation:
 - WITH p-stop: drops by ~3 orders of magnitude
 - WITHOUT p-stop: drops by ~6 orders of magnitude;
variation of approx. 1 order of magnitude has been observed
 - ➔ p-stop provides better inter-pixel isolation after irradiation
 - ➔ WITHOUT p-stop, we can still get a resistance $\sim 100 \text{ M}\Omega$
 - temperature dependence has been observed
 - ➔ the influence needs to be considered as a systematic error
- Is p-stop necessary?
 - ➔ Improvements of the experiment and further investigations are required